

Docket No. 209291US0

IN RE APPLICATION OF: Hiroyuki NAGASAWA, et al.

SERIAL NO: 09 867,467

FILED: May 31, 2001

FOR: METHOD OF MANUFACTURING SILICON CARBIDE, SILICON CARBIDE, COMPOSITE MATERIAL,
AND SEMICONDUCTOR ELEMENT

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Transmitted herewith is an amendment w/attached marked-up copy in the above-identified application.

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MAR 07 2003

TC 1700

☐ No additional fee is required

☐ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.

☒ Additional documents filed herewith: Letter Requesting Approval of Drawing Changes: Figure 7 (w/corrections in red)

The Fee has been calculated as shown below:

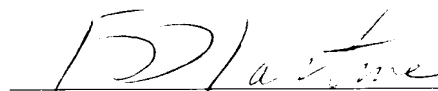
CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS	RATE	CALCULATIONS
TOTAL	16	MINUS	20	0	x \$18 =	\$0.00
INDEPENDENT	3	MINUS	3	0	x \$84 =	\$0.00
		<input type="checkbox"/> MULTIPLE DEPENDENT CLAIMS			+ \$280 =	\$0.00
		TOTAL OF ABOVE CALCULATIONS				\$0.00
		<input type="checkbox"/> Reduction by 50% for filing by Small Entity				\$0.00
		<input type="checkbox"/> Recordation of Assignment			+ \$40 =	\$0.00
		TOTAL				\$0.00

☐ A check in the amount of \$0.00 is attached.

☒ Please charge any additional Fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

☒ If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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MAR 04 2003

DOCKET NO.: 209291US0

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

Hiroyuki NAGASAWA et al

SERIAL NO.: 09/867,467

FILED: May 31, 2001

:

: GROUP: 1765

: EXAMINER: M. Song

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FOR: METHOD OF MANUFACTURING SILICON CARBIDE,
SILICON CARBIDE COMPOSITE MATERIAL,
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LETTER REQUESTING APPROVAL OF DRAWING CHANGES

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Please review for approval the proposed changes to the Formal Drawings shown in RED on the attached photocopies of the drawings. Once these changes have been reviewed and approved by the Examiner in charge of this case, instructions for their implementation will be forwarded to an approved bonded draftsman.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



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